

Amendments to the Specification:

Please amend the paragraph at page 21, line 24, to page 22, line 3, as follows:

The supply pump supplies the solution up to the top portion of the nozzle 21 with the supply pressure maintained so that the solution does not appear from the top portion of each nozzle 21 (to an extent that a convex meniscus is not formed) when the convex meniscus generator 40 and the ejection voltage supply ~~40~~ 25 are not operated.

Please amend the paragraph at page 22, line 19, to page 23, line 8, as follows:

The ejection voltage supply 25 includes an ejection electrode 28 for applying an ejection voltage provided at a boundary position between the solution chamber 24 and the inside-nozzle flow passage 22 inside the liquid ejection head 26, and a pulse voltage supply 30 for applying a rapidly rising pulse voltage as an ejection voltage to the ejection electrode 28. The ejection head 26 has a layer that forms nozzles 21, and a layer that forms the solution

chambers 24 and the supply channels 27, and a description will be given in detail later. The ejection electrode 28 is provided at the entire boundary of these layers. With this structure, the single ejection electrode 28 contacts the solution within all solution chambers 24, thereby charging the solution guided to all nozzles 21 by application of ejection voltage to the single ejection electrode ~~24~~ 28.

Please amend the paragraph at page 24, line 19, to page 25, line 7, as follows:

For the flexible base layer 26a, there may be employed flexible material as described above, for example, a metal thin plate. The reason for requiring such flexibility is that later described piezoelectric elements 41, of the convex meniscus generators 40 are provided at the positions on the outer surface of the flexible base layer 26a and corresponding to the solution chambers 24 to bend the flexible base layer 26a. That is, a predetermined voltage is applied to the piezoelectric element ~~21~~ 41 to bend the flexible base layer 26a both inward or outward at above-described position, which causes the inner volume of the solution chamber 24 to decrease or increase, so that

change of inner pressure enables formation of the convex meniscus of solution at the top portion of the nozzle 21, or enables the solution to be drawn in.

And please amend the paragraph at page 29, lines 4-10, as follows:

The convex meniscus generator 40 includes a piezoelectric element 41 as a piezoelectric transducer disposed on the outer surface (lower surface in FIG. 1) of the flexible base layer 26a of the ~~nozzle plate~~ liquid ejection head 26 and at the position corresponding to the solution chamber 24, and a drive voltage supply 42 to apply a rapidly rising drive pulse voltage to deform the piezoelectric element 41.